Supplementary Material (ESI) for Journal of Materials Chemistry

Supporting Information

Direct fabrication of 3D silica-like microstructures from epoxy-functionalized polyhedral oligomeric silsesquioxane (POSS)

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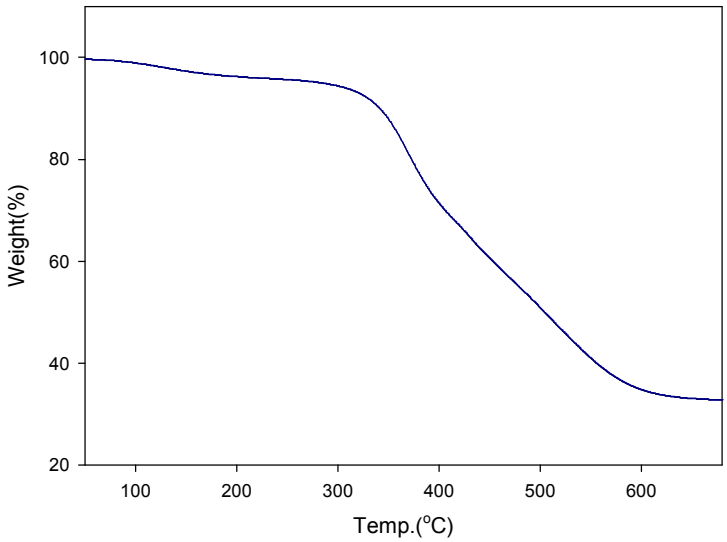

Figure S1. Thermogravimetric analysis of epoxy-POSS photoresist in air environment. The relative volume was measured by increasing the temperature up to 700 °C at a heating rate of 10 °C/min.